Docket: IB-1826A

**Amendments to the Abstract** 

A radio frequency (RF) driven plasma ion source has an external RF antenna, i.e.

Please replace the Abstract with the following amended Abstract:

the RF antenna is positioned outside the plasma generating chamber rather than inside.

The RF antenna is typically formed of a small diameter metal tube coated with an insulator. A flange An external RF antenna assembly is used to mount the external RF antenna to the ion source. The RF antenna tubing is wound around the external RF antenna assembly flange is formed of a material, e.g. quartz, that which is essentially transparent to the RF waves.

The external RF antenna assembly flange is attached to and forms a part of the plasma

the plasma chamber and ionize a gas contained therein. The plasma ion source is

source chamber so that the RF waves emitted by the RF antenna enter into the inside of

typically a multi-cusp ion source. A converter can be included in the ion source to

produce negative ions.

Enclosed:

Replacement Abstract

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